

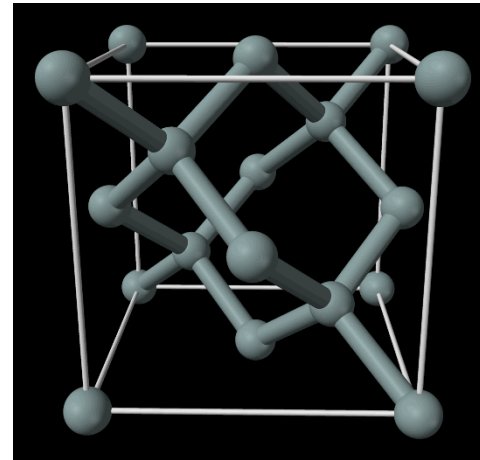
EFFECTS OF SINGLE ION STRIKES INTO SI ON THE $3D$ RECIPROCAL SPACE - UPDATE

Question?

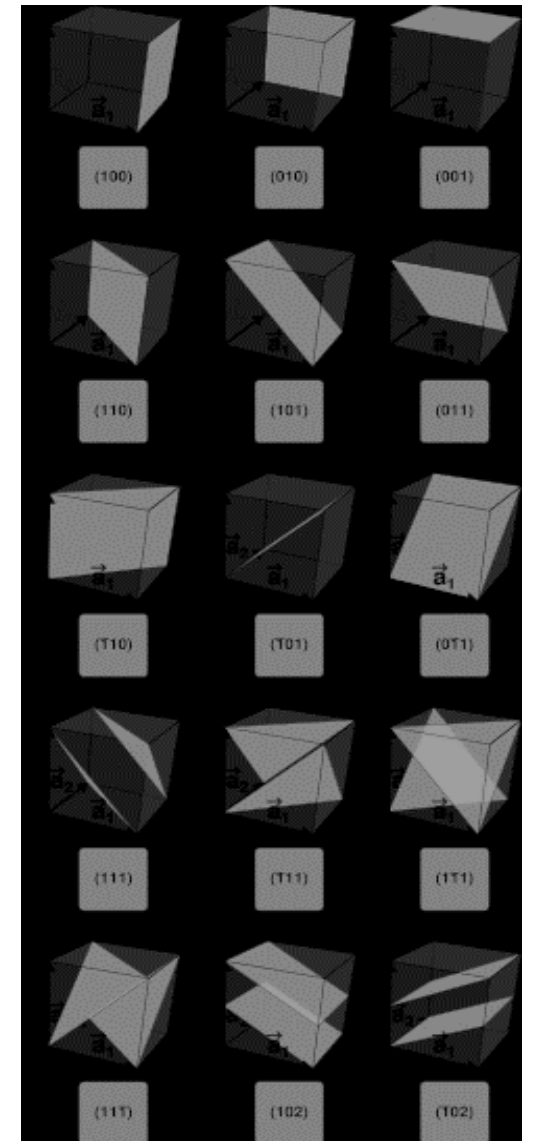
How does Si behave at the atomistic level during single ion strikes and how does this affect the 3D Reciprocal Space?

Real Space

- In Real Space a unit cell is made up of atoms
- With a real distance, \AA
- You can look at different planes of the crystal according to the miller indices (hkl)
- In what way can we extract crystallographic information?
 - Electron Diffraction in a TEM



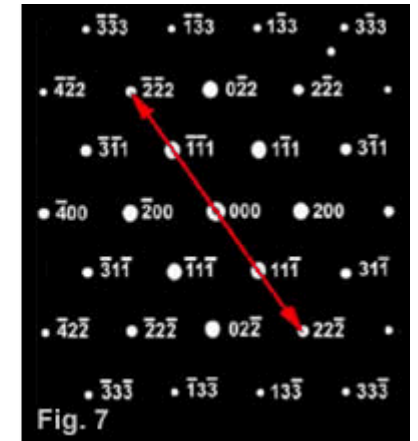
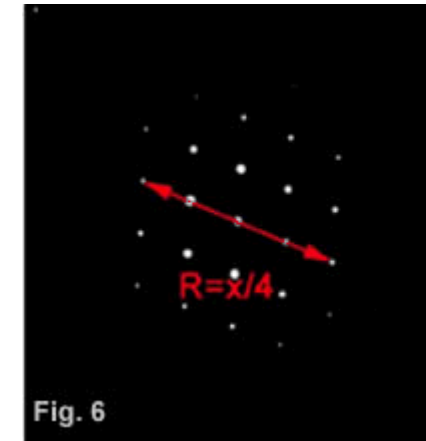
Real Space Unit Cell of Silicon [1]



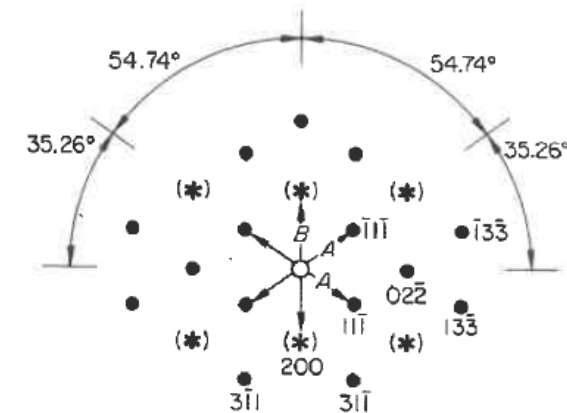
Miller Indices for a cubic cell [2]

Reciprocal Space

- In reciprocal space these individual planes in real space become diffraction spots in 3D space, a.k.a. a reciprocal lattice.
- Distance is now $1/d$.
- Furthermore the different patterns are determined by zone axes which is a direction normal to the planes of interest



Real SAED pattern along [011]. [4]

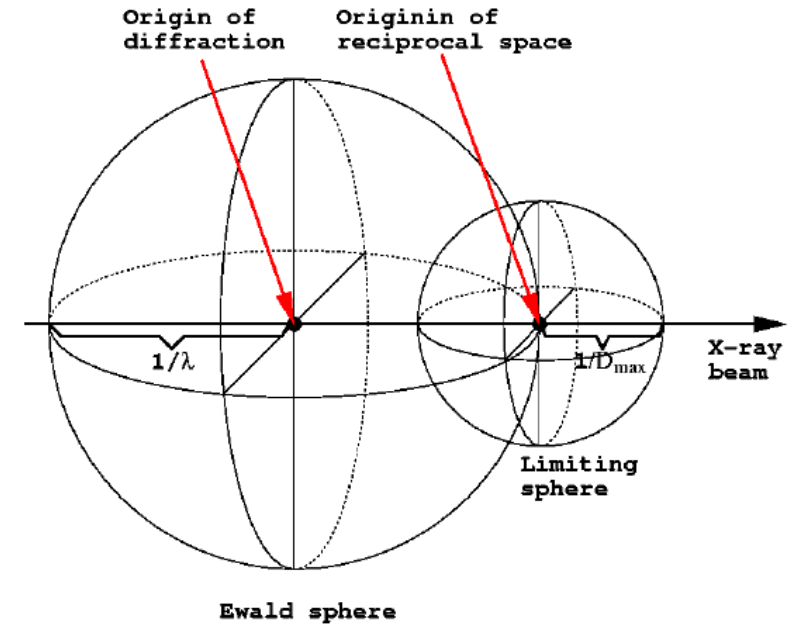


(b) $\frac{B}{A} = \frac{2}{\sqrt{3}} = 1.155 \quad B = z = [0 \ 1]$

[011] Zone Axis in a diamond structure [3]

Ewald Sphere & Laue Conditions

- The Ewald Sphere is an imaginary construct by which when its conditions are met generate an SAED as everywhere it comes in contact on the reciprocal lattice is a diffraction spot
- Laue Conditions determine how far out diffraction spots will occur in a pattern



Interaction of Ewald Sphere and Reciprocal Lattice in 3D space [5]

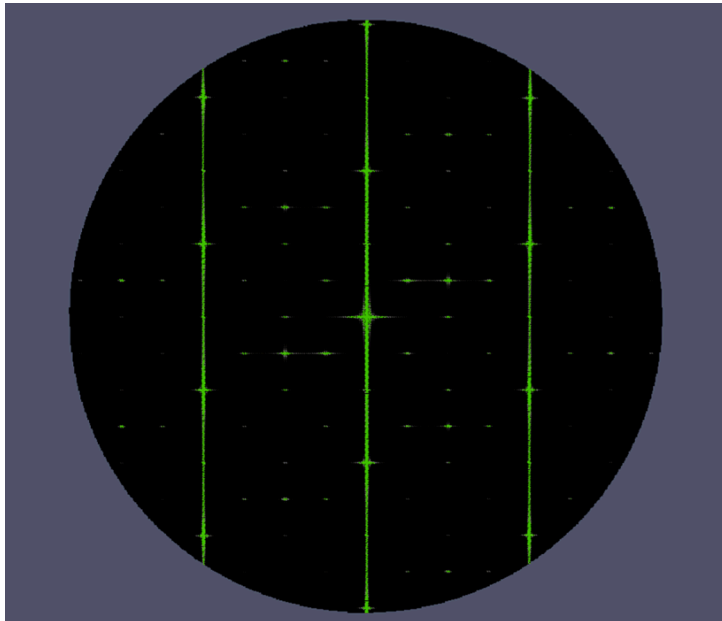
Goal

- Compare a perfect single crystal silicon reciprocal lattice to that of irradiated silicon
- When studying the diffraction patterns is there noticeable peak shifting or broadening in the irradiated samples in the planes of interest
- Quantifying the amount of micro or macro strain occurring in the form of peak broadening or peak shifting

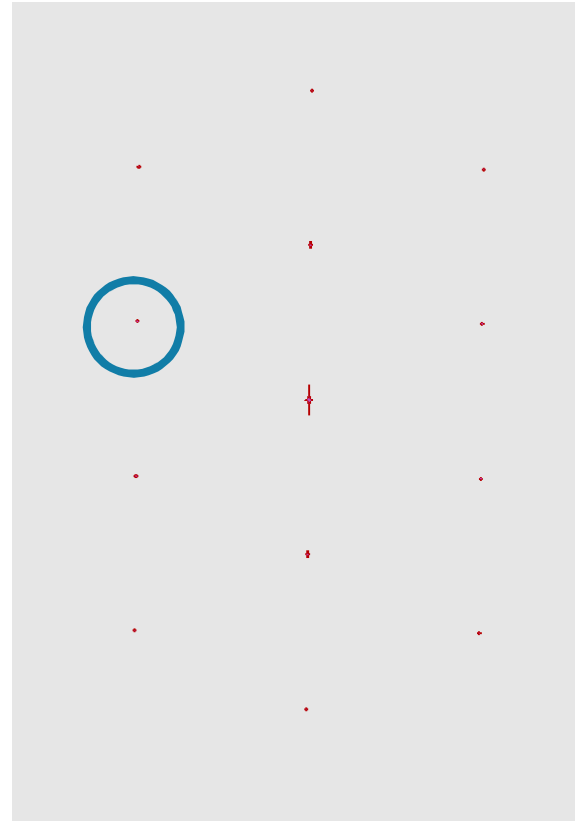
Progress Updates

- Purpose: Validate MD simulation can correctly generate SAED patterns
- Problem: SAED patterns being generated were not aligning with known SAED patterns
- Solution: Threshold intensity to minimum 10,000 to reduce noise yet not cut off signal
 - In addition correctly scale intensity range to show distribution.
 - Value of 10,000 is approximately 0.2% of maximum intensity
 - More thresholding can be done later if necessary in the process
- Outcome: Model SAED of perfect silicon align with Eddington reference patterns
 - Shown by matching 2 distinct angles on each pattern

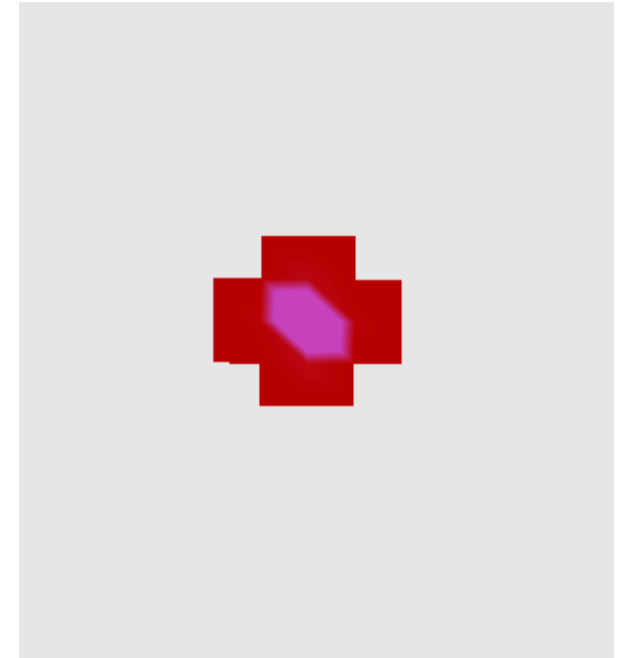
Before → After



[012] Raw Data has a lot of noise

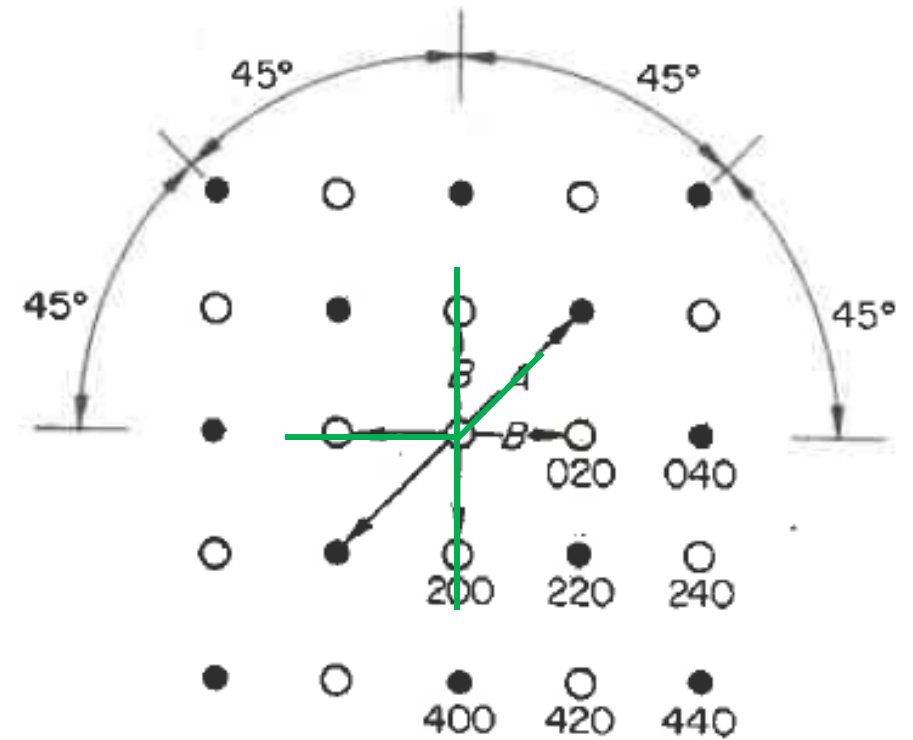
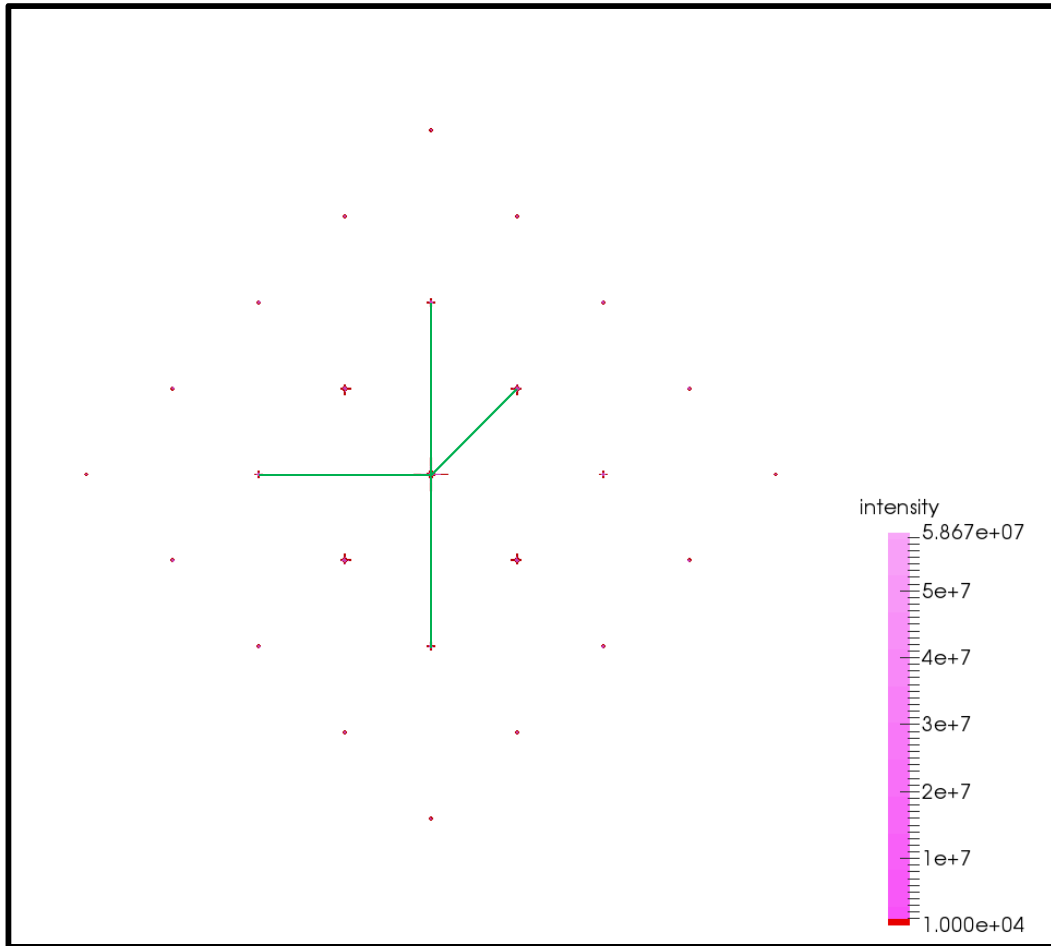


[012] Thresholded at 10k to remove most noise but not signal



$\langle \bar{2}\bar{4}2 \rangle$ in [012] Showing distinct diffraction spot surrounded by some noise

[001]

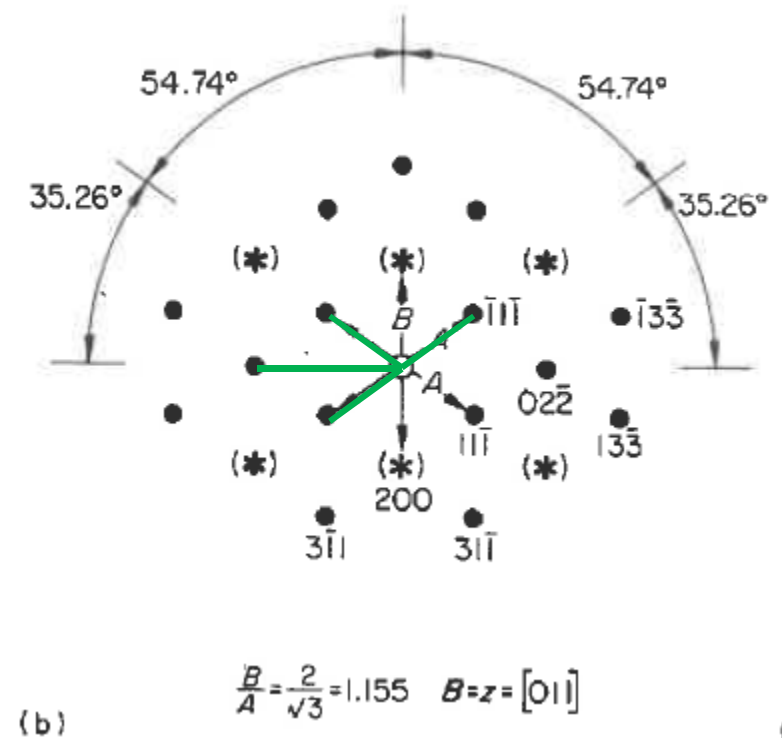
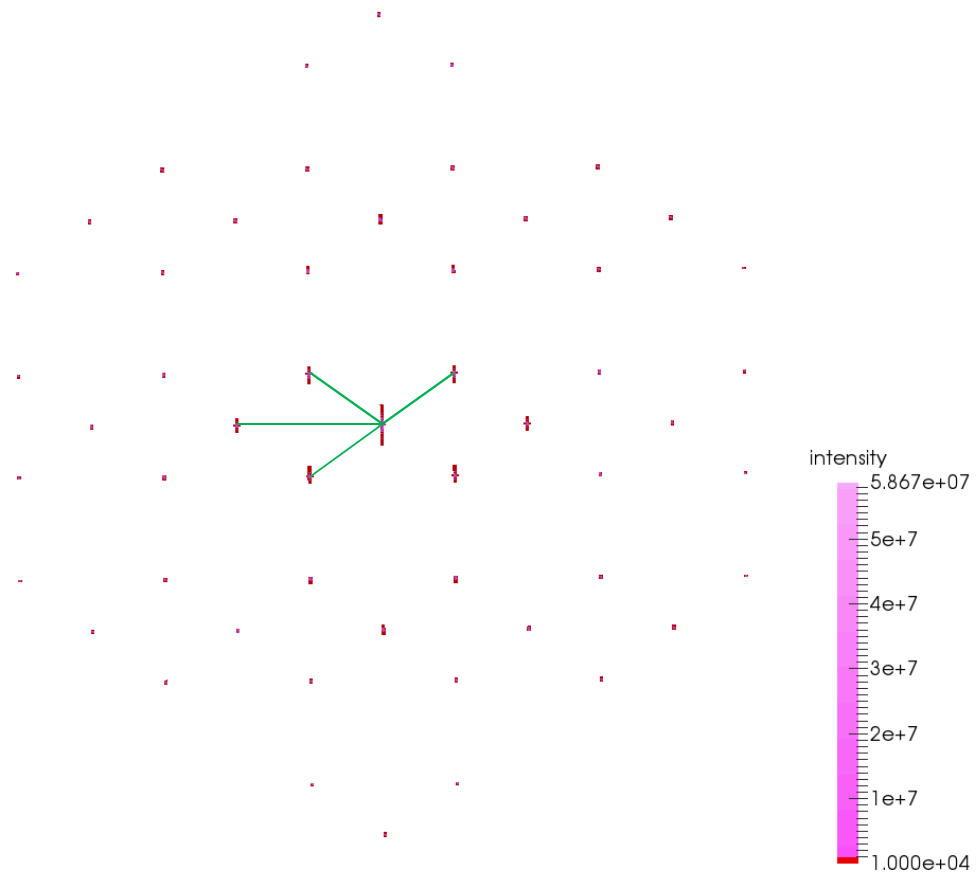


(a)

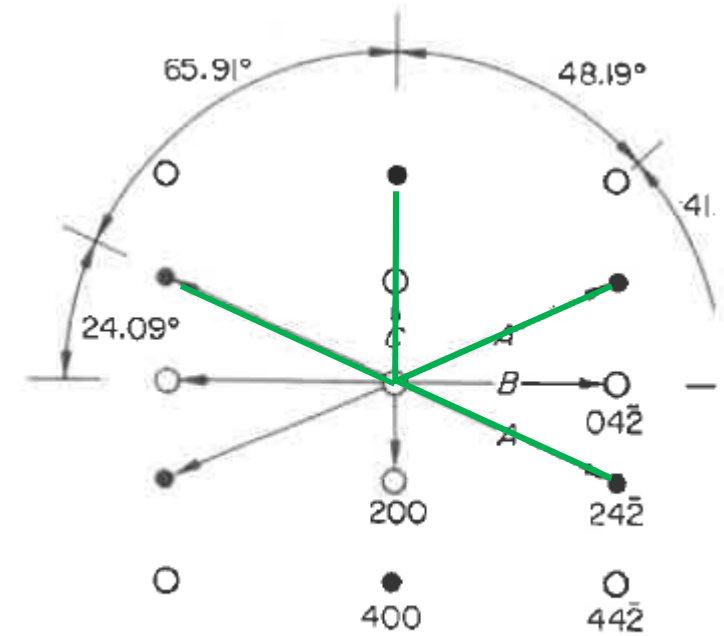
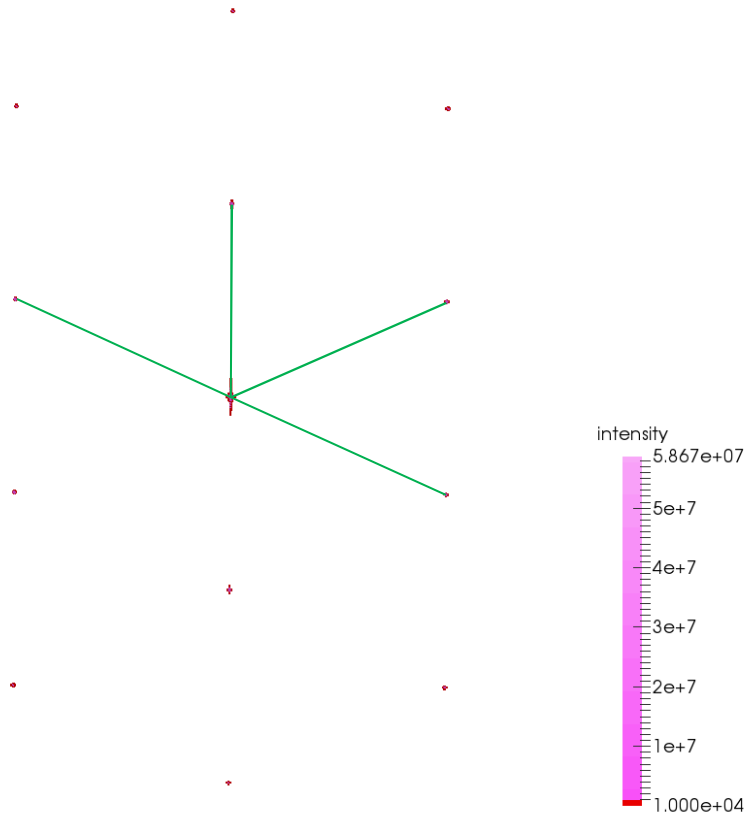
$$\frac{A}{B} = \frac{\sqrt{2}}{1} = 1.414 \quad B = z = [001]$$

Note: Because of zooming in to see SAED patterns in Paraview. Distances will be off but angles stay true and show that patterns match

[011]

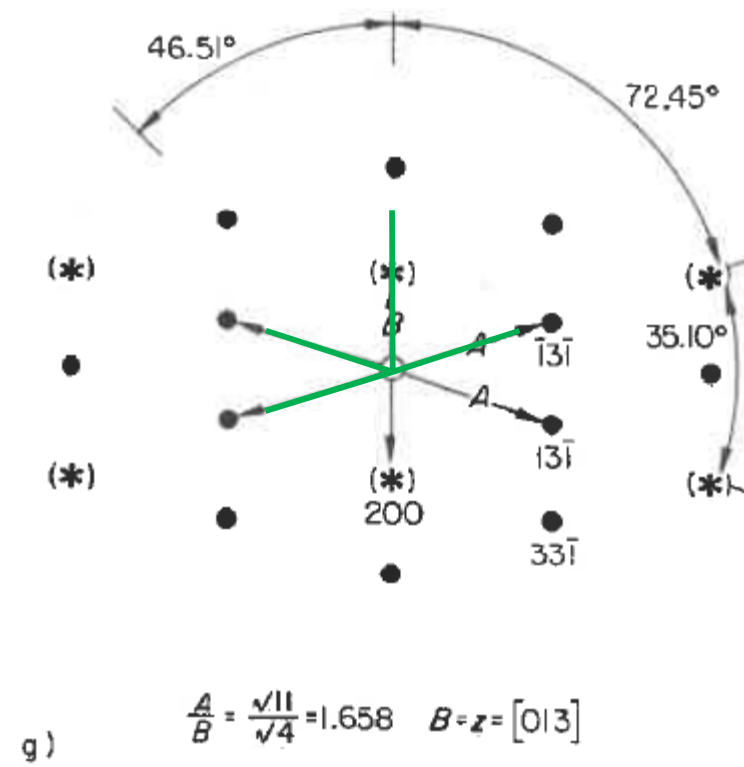
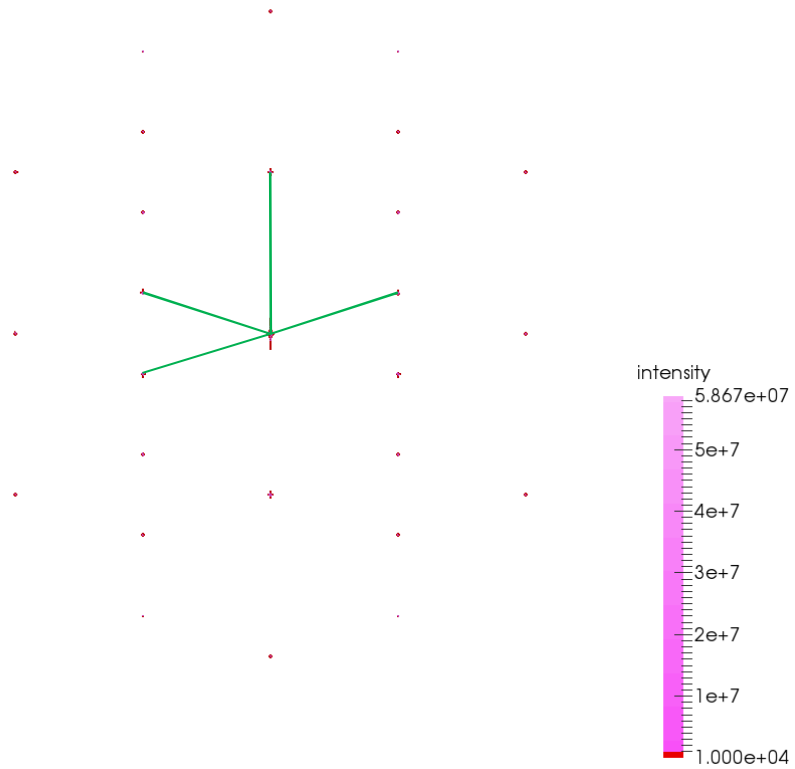


[012]

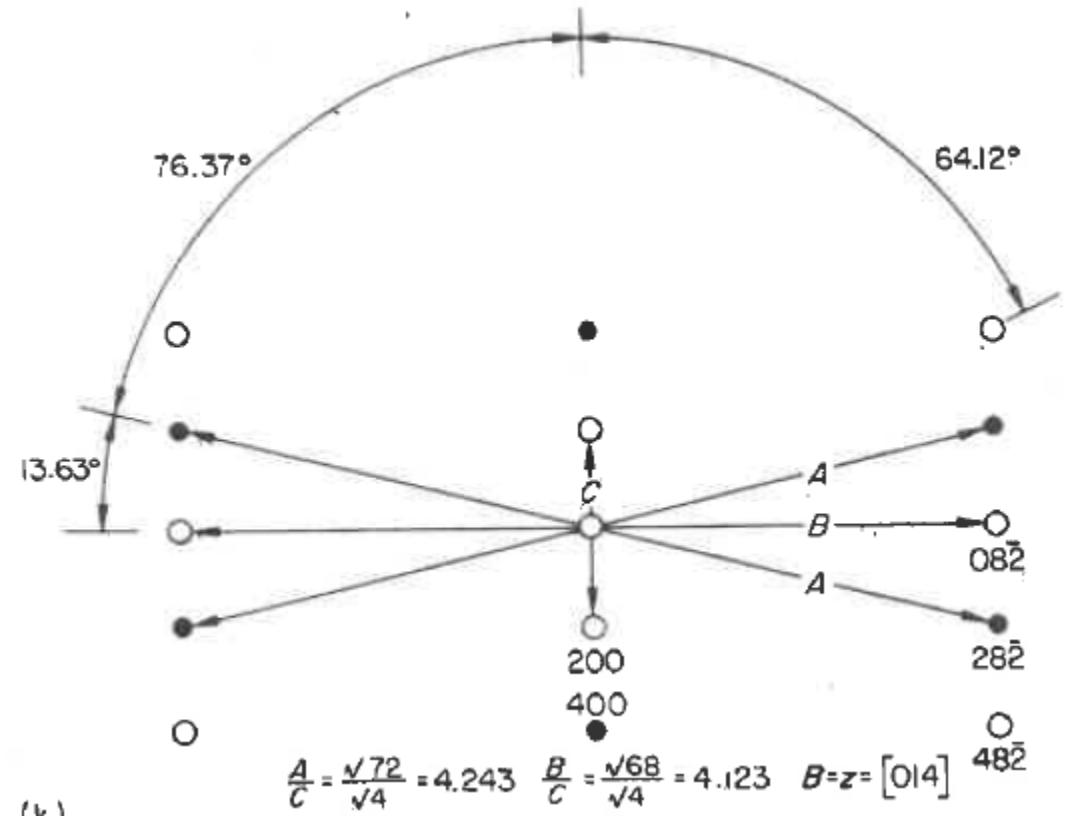
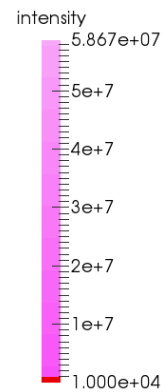


(d) $\frac{A}{C} = \frac{\sqrt{24}}{\sqrt{4}} = 2.450$ $\frac{B}{C} = \frac{\sqrt{20}}{\sqrt{4}} = 2.236$ $B = z = [012]$

[013]



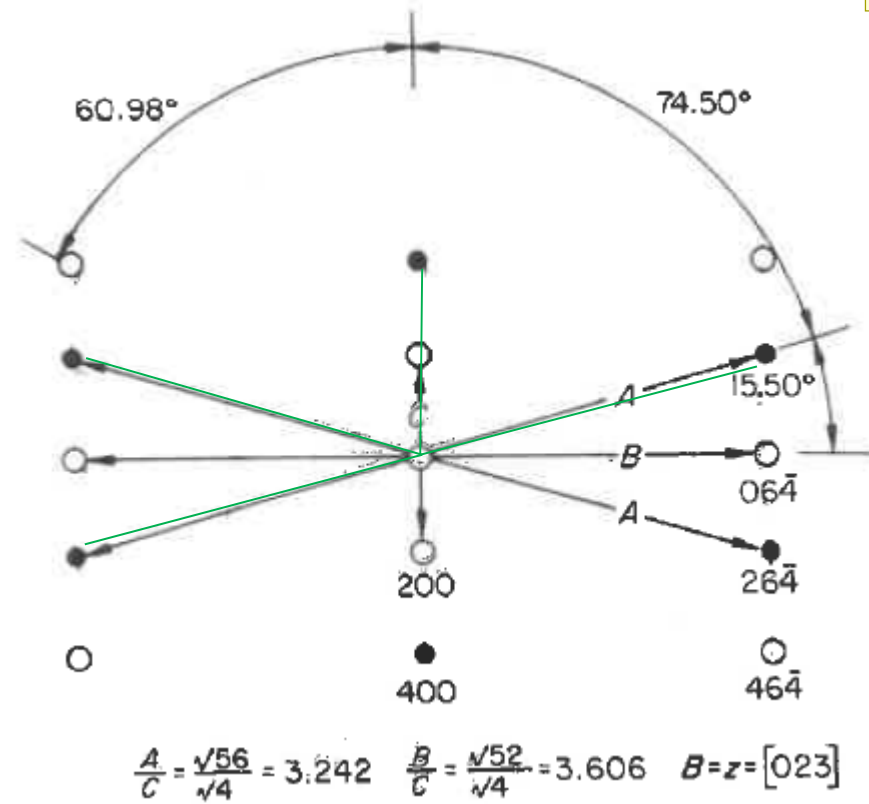
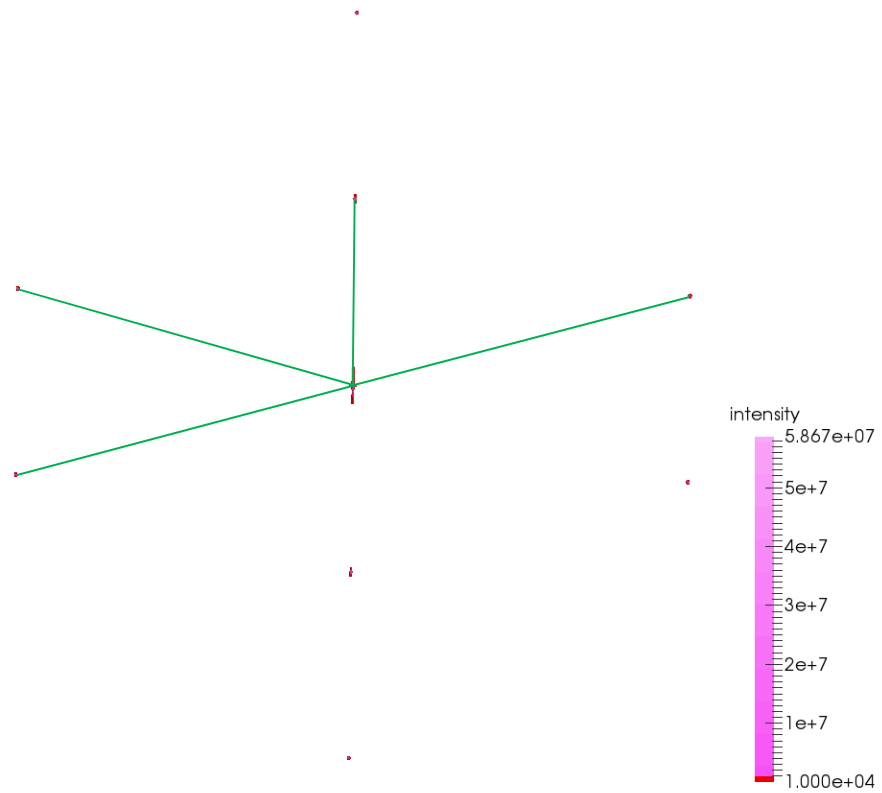
[014]



Reason for no exact match is likely due to thresholding value to remove noise and retain signal. No other reference SAED pattern has planes that go out as far as <#8#>

[023]

FMU1



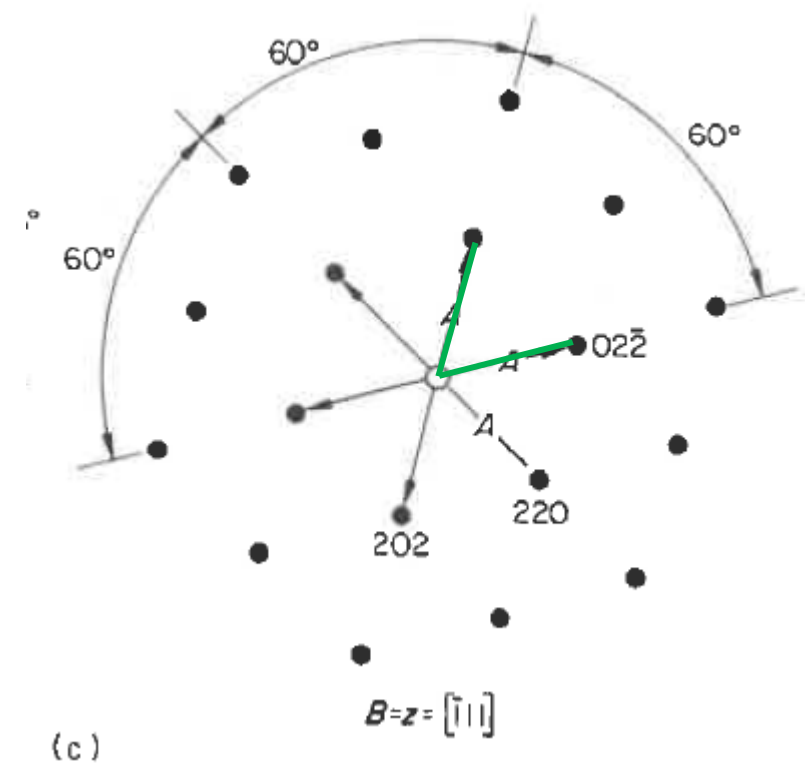
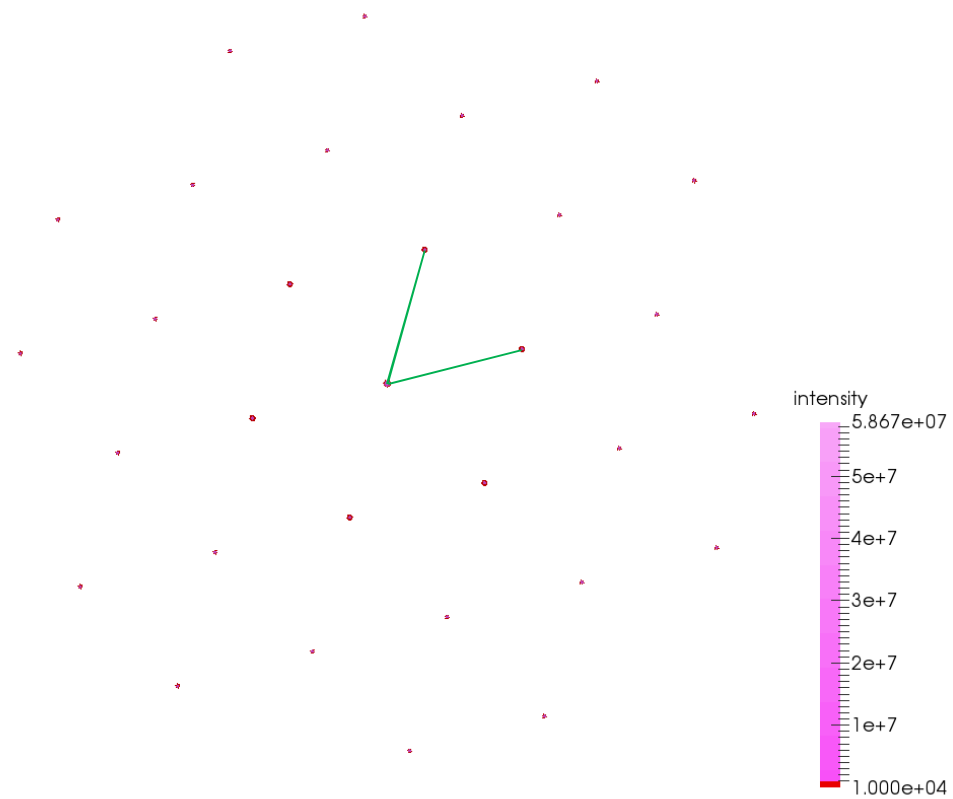
Slide 14

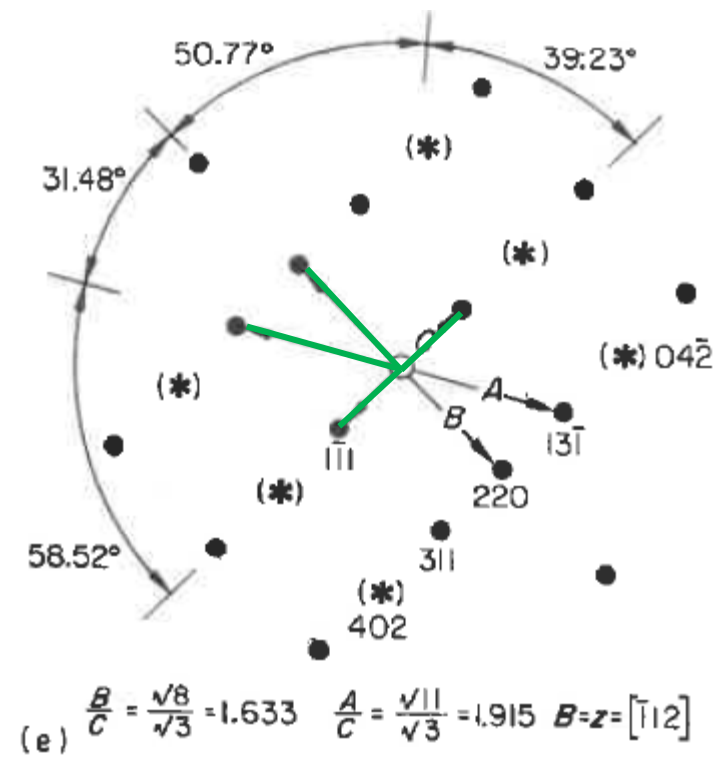
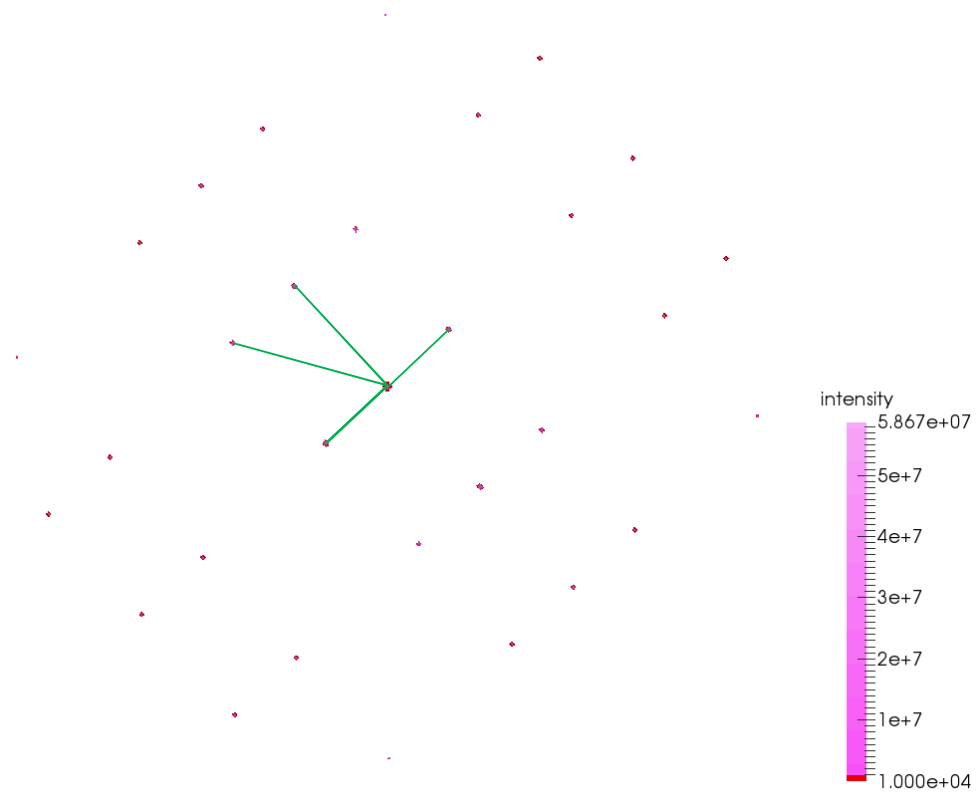
FMU1

check this

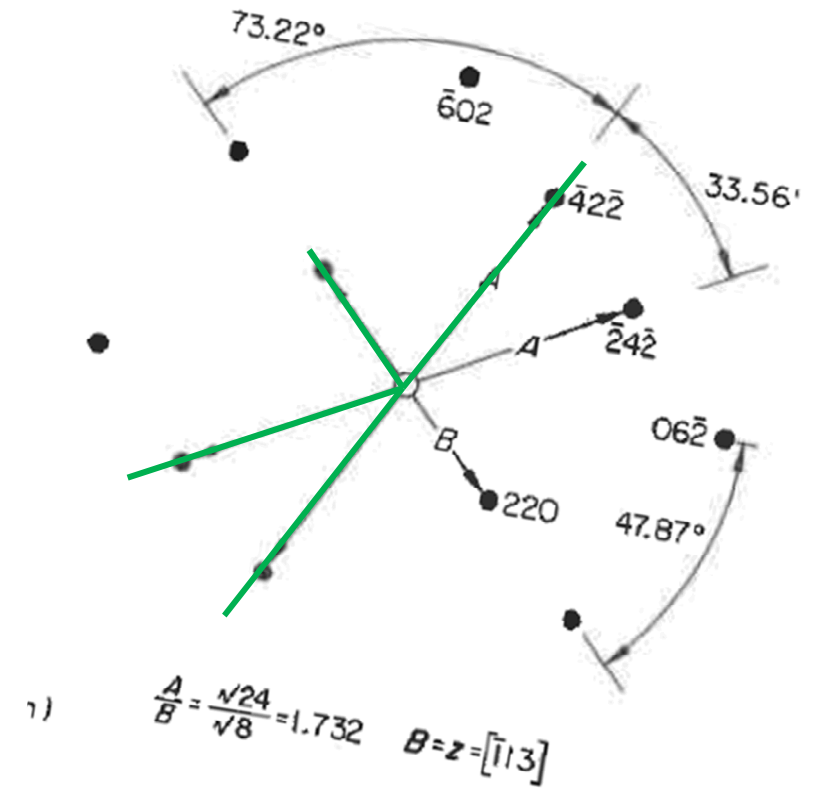
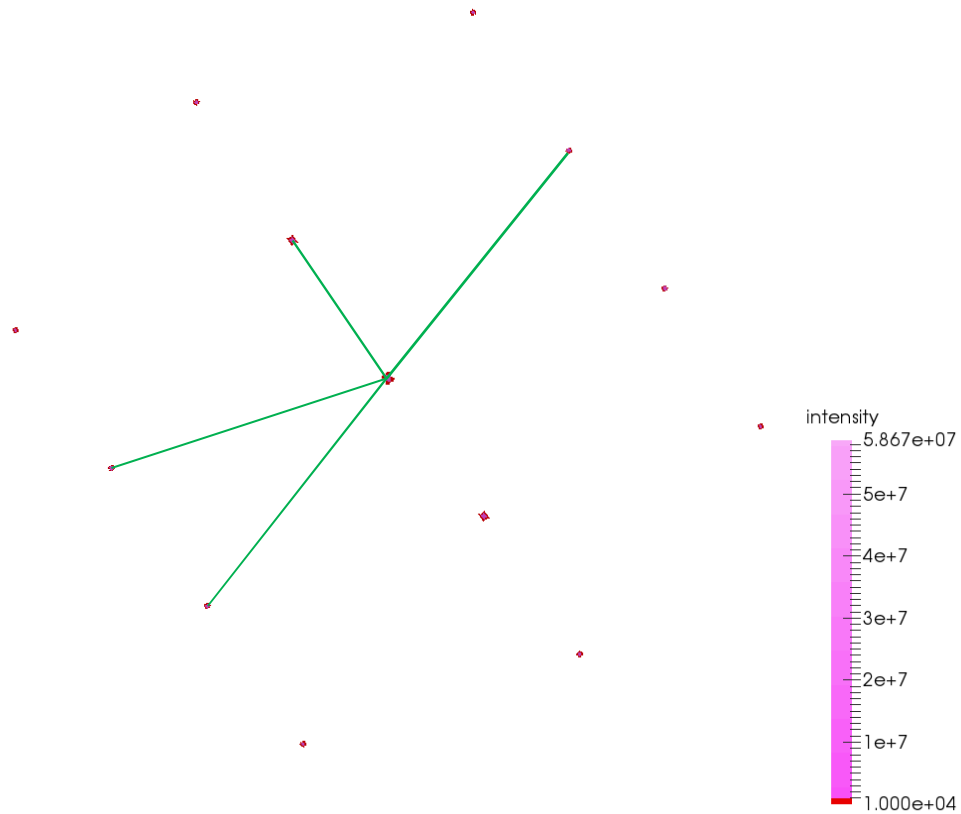
Franco, Manuel Uriel, 1/11/2017

$[\bar{1}11]$

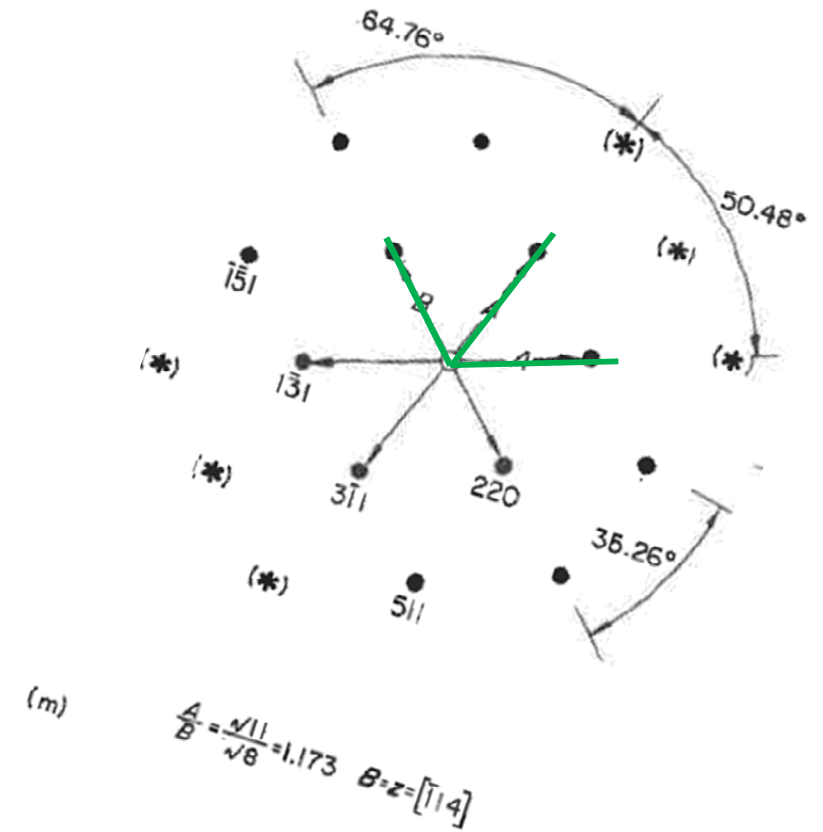
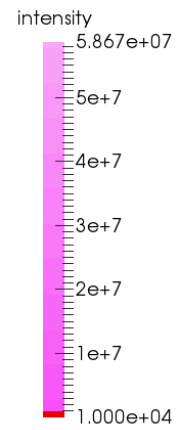
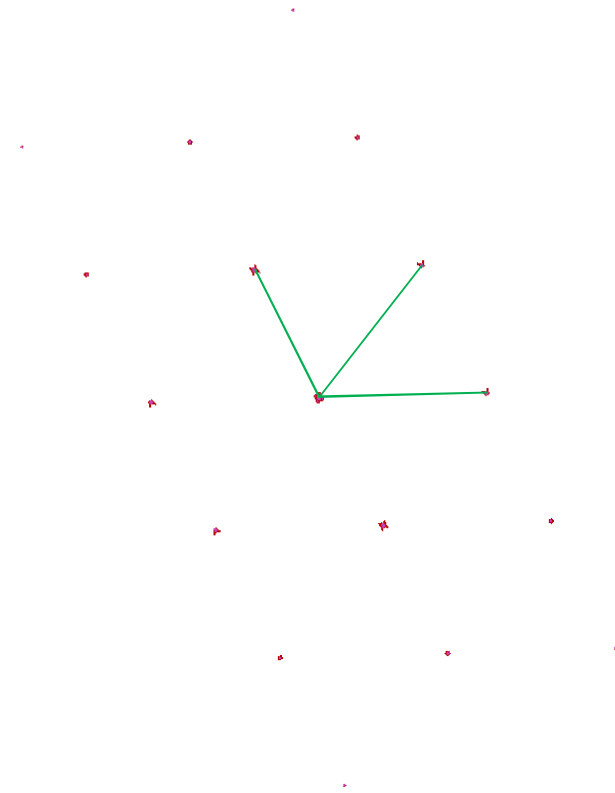


$$[\bar{1}12]$$


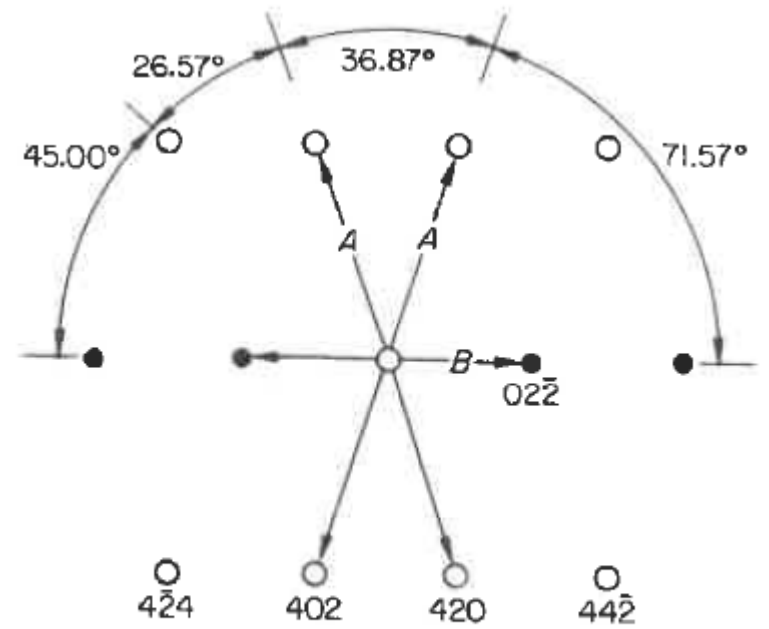
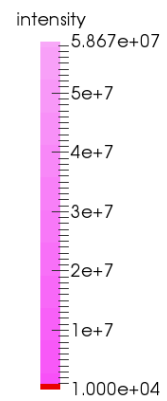
$[\bar{1}13]$



$[\bar{1}14]$

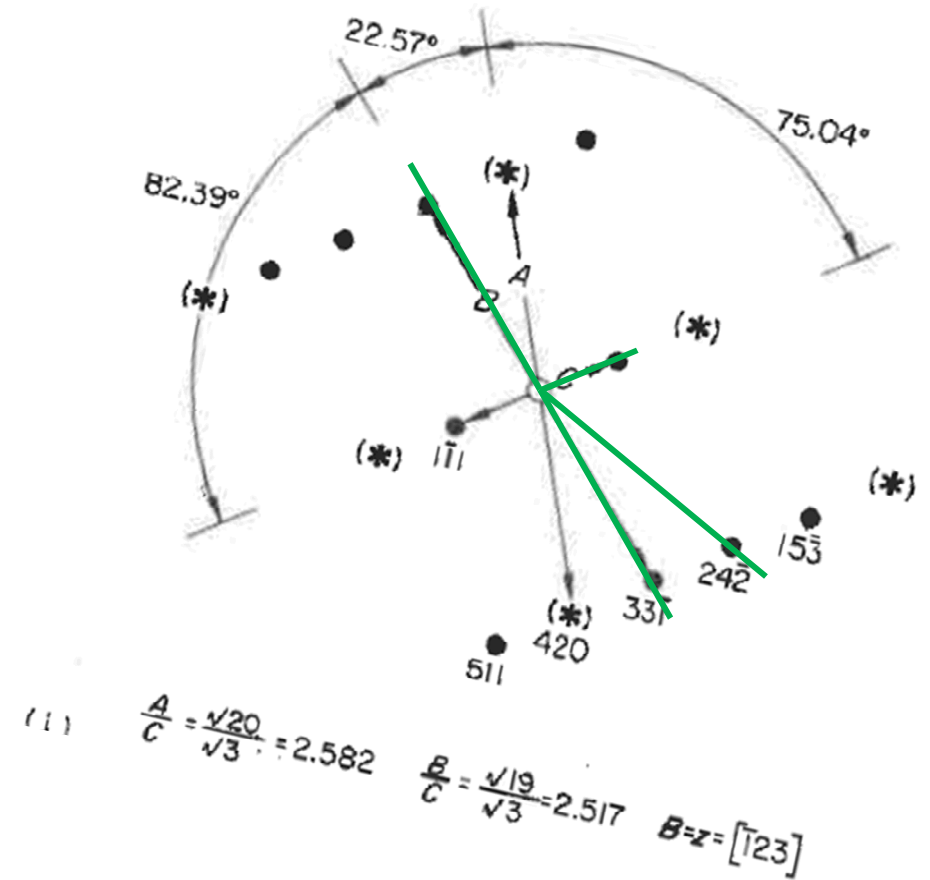
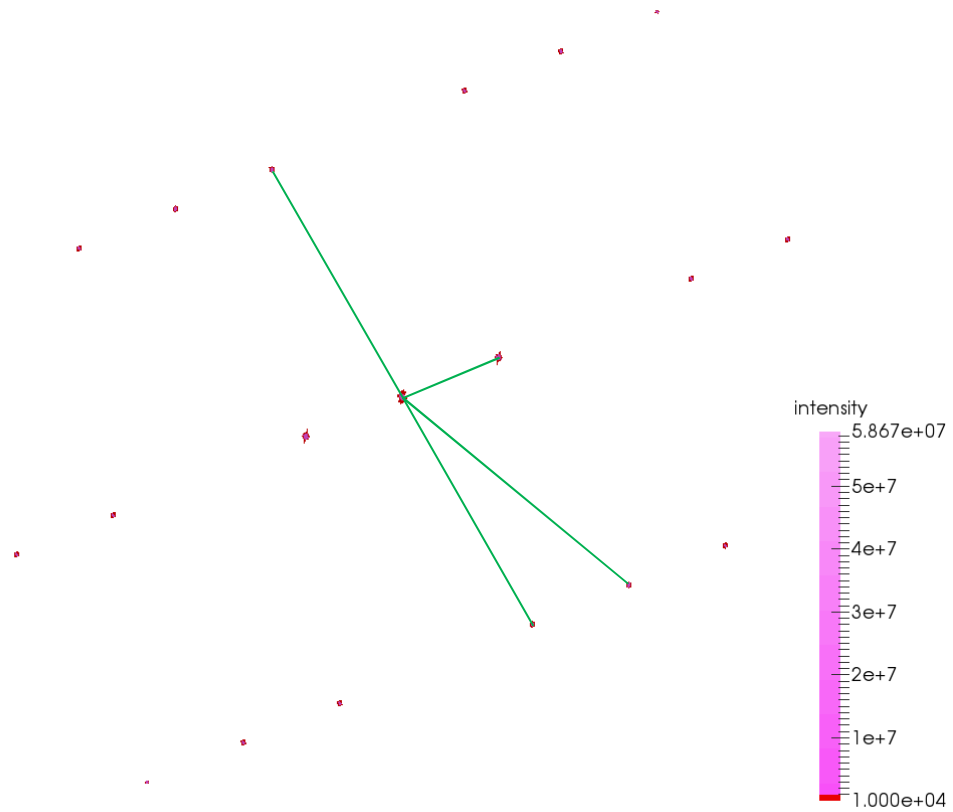


$[\bar{1}22]$

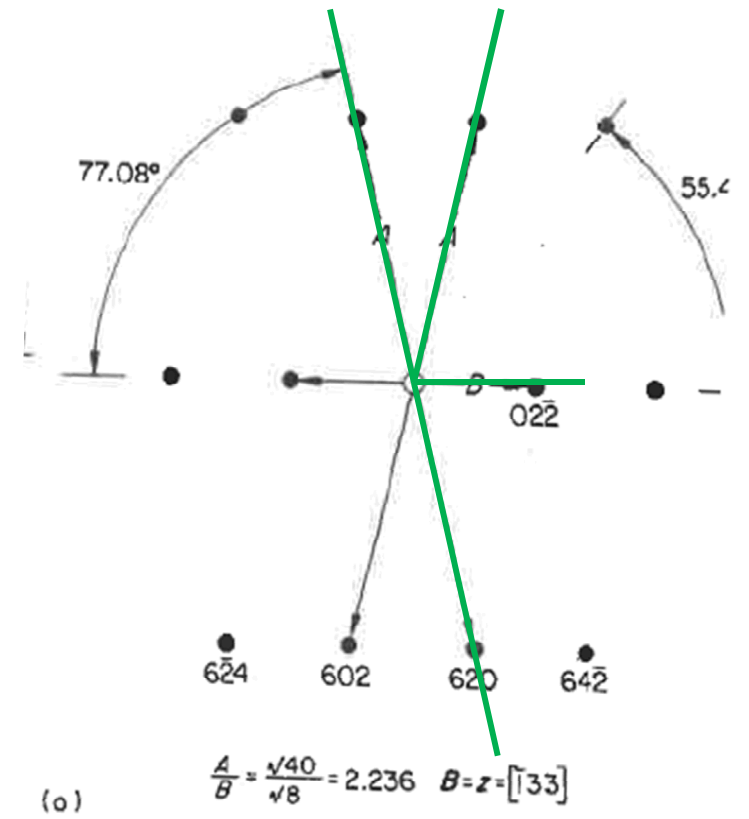
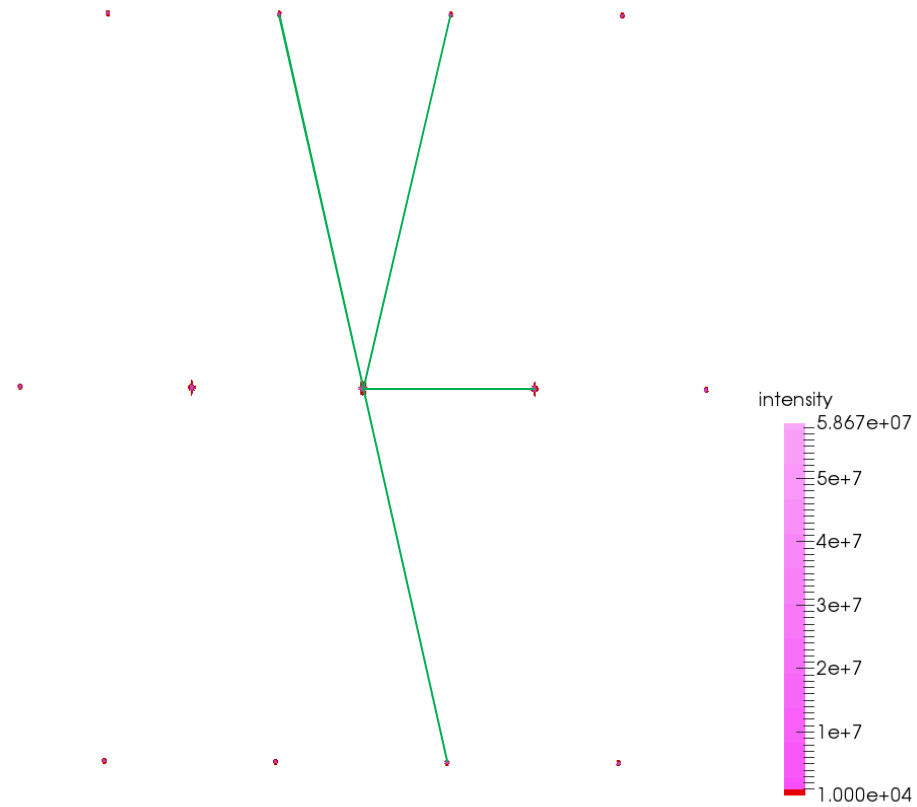


(f) $\frac{A}{B} = \frac{\sqrt{20}}{\sqrt{8}} = 1.581 \quad B = z = [\bar{1}22]$

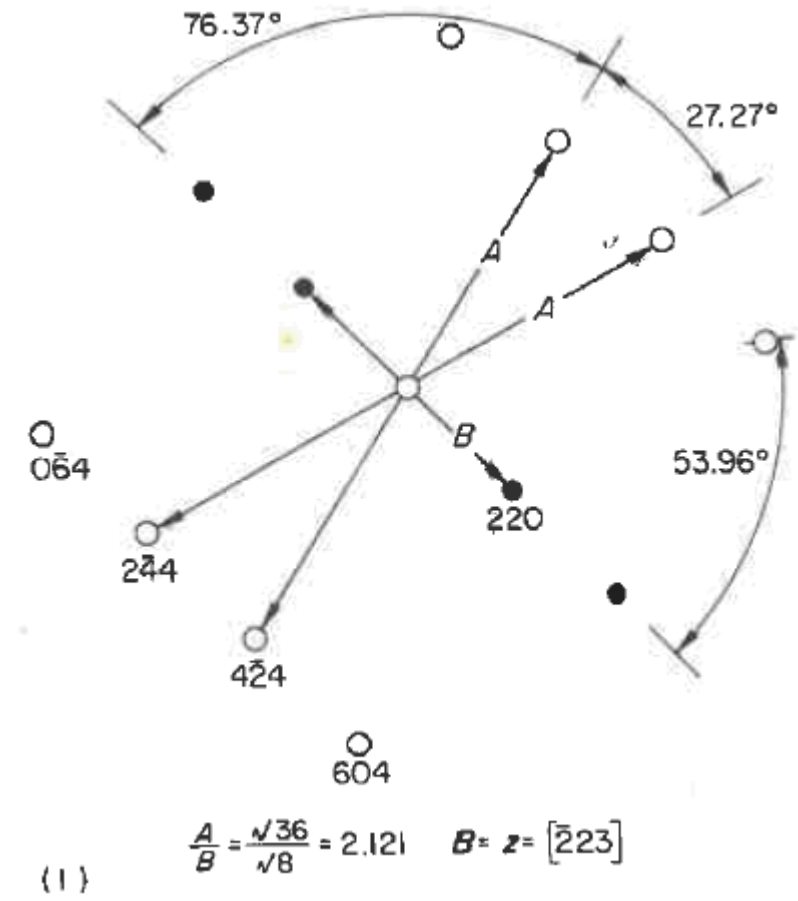
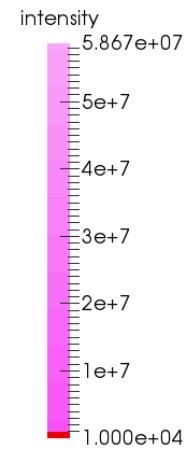
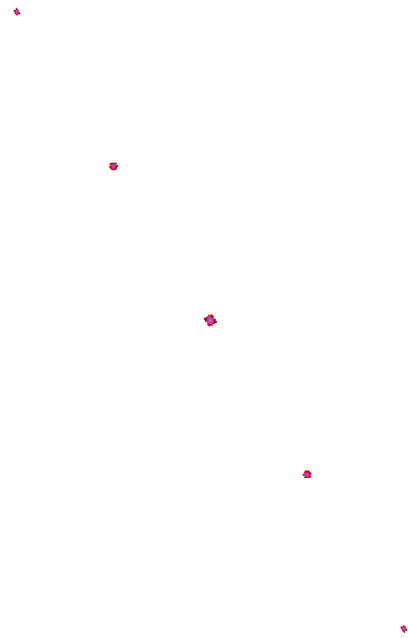
$[\bar{1}23]$



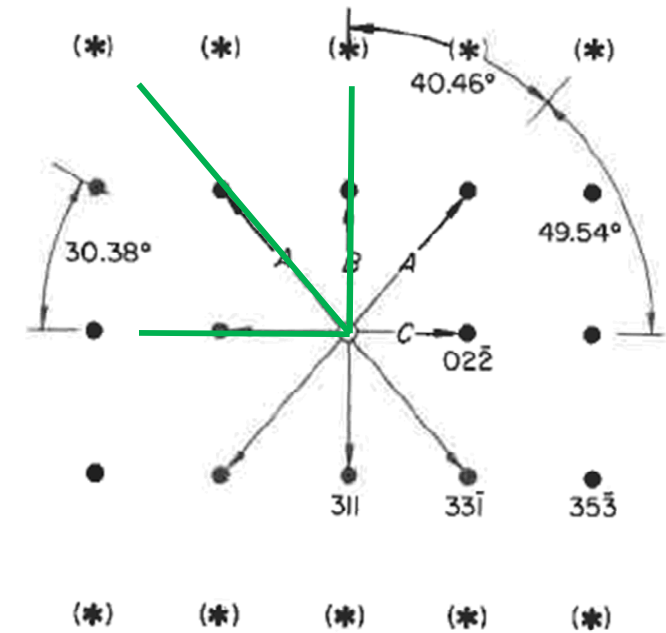
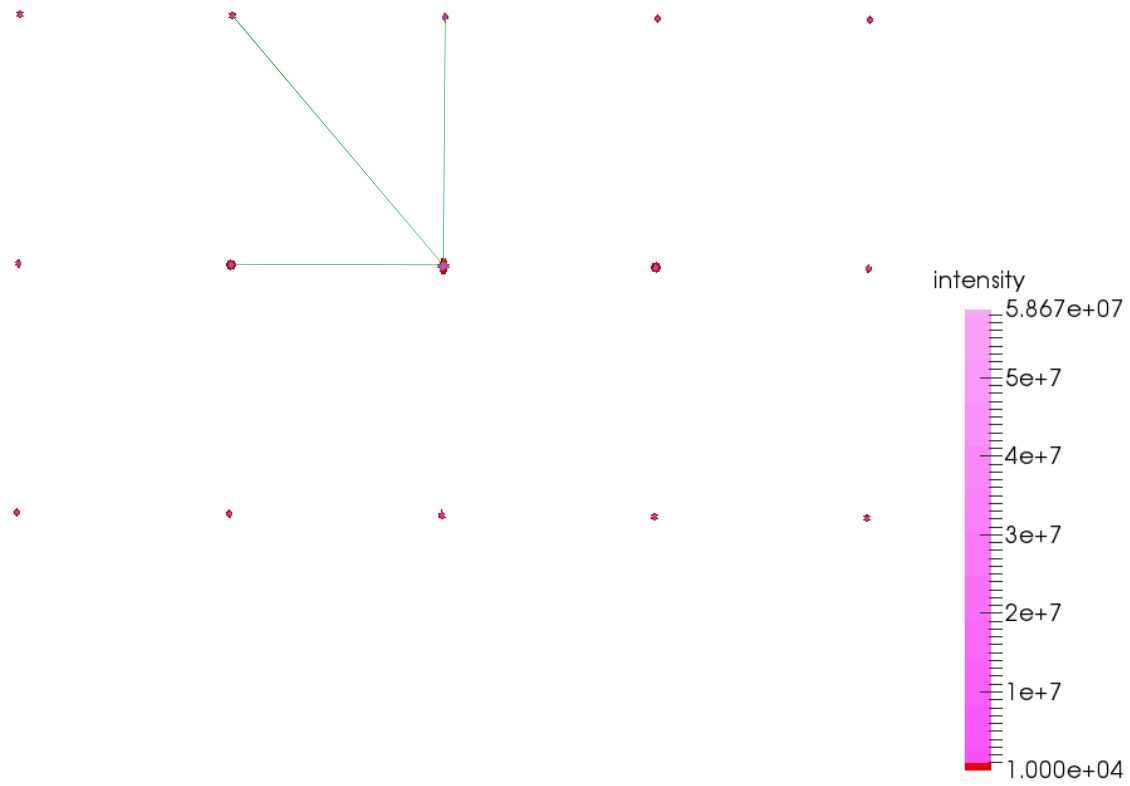
$[\bar{1}33]$



$[\bar{2}23]$



$[\bar{2}33]$



(n) $\frac{A}{C} = \frac{\sqrt{19}}{\sqrt{8}} = 1.541$ $\frac{B}{C} = \frac{\sqrt{11}}{\sqrt{8}} = 1.173$ $B = z = [\bar{2}33]$

Next Steps

- Generate algorithm or scripts to quickly identify center of diffraction points on an SAED pattern corresponding to known d-spacings and planes.
 - Using ParaView isolate a volume of space surrounding a diffraction sphere using the identified center points
 - Take difference of (Damaged – Perfect) Diffraction Sphere to identify peak shifting or peak broadening phenomena
 - Generate algorithm to make 2 separate difference pole plots (one for broadening and one for shifting) to identify planes of interest that would drive future experimental work from the modeling data

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